

Abstract of the Disclosure

A method for the nondestructive measurement of the thickness of thin layers having a probe, having a first coil device on an inner core, the geometrical center of which coil device and the geometrical center of at least one second coil device coincide, the at least one second coil device partially surrounding the first coil device, and an evaluation unit, to which signals of the coil devices are emitted during a measurement for ascertaining the layer thickness. A circuit is provided, by which the first and the at least one second coil devices are excited sequentially during a measurement.

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